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JUN 23 2009

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: OZAKI, Takashi, et al.

Group Art Unit: 1792

Serial No.: 10/528,137

Examiner: MACARTHUR, Sylvia

Filed: December 12, 2005

P.T.O. Confirmation No.: 2307

FOR: SUBSTRATE PROCESSING APPARATUS AND METHOD FOR
MANUFACTURING A SEMICONDUCTOR DEVICEAMENDMENT UNDER 37 CFR §1.111Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

June 23, 2009

Sir:

In response to the Office Action dated March 31, 2009, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 11 of this paper.